



PATENT
0941-0306P

IN THE U.S. PATENT AND TRADEMARK OFFICE

Applicant: CHEN, Shun-An et al. Conf.: 1826
Appl. No.: 09/930,971 Group: 2863
Filed: August 17, 2001 Examiner: Xiuquin Sun
For: A SYSTEM FOR DYNAMICALLY MONITORING THE
STABILITY OF SEMICONDUCTOR
MANUFACTURING EQUIPMENT

#4/1a
RECEIVED
JUL -8 2002
TECHNOLOGY CENTER 2800

REPLY UNDER 37 C.F.R. § 1.111

Assistant Commissioner for Patents
Washington, DC 20231

July 3, 2002

Sir:

Responsive to the April 3, 2002 Office Action, the following amendments and remarks are respectfully submitted in connection with the above-identified application.

IN THE ABSTRACT OF THE DISCLOSURE:

Please replace the Abstract of the Disclosure with the rewritten Abstract of the Disclosure located below:

--ABSTRACT OF THE DISCLOSURE

Q1 A system for dynamically monitoring the stability of manufacturing equipment including a process executor requesting a plurality of semi-manufactured products processed by the manufacturing equipment to be inspected at a first sampling rate